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Nanotechnologies — Measurements of particle size and shape distributions by scanning electron microscopy

*Nanotechnologies — Détermination de la distribution de taille et de
forme des particules par microscopie électronique à balayage*



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ISO copyright office
CP 401 • Ch. de Blandonnet 8
CH-1214 Vernier, Geneva
Phone: +41 22 749 01 11
Email: copyright@iso.org
Website: www.iso.org

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Foreword

ISO (the International Organization for Standardization) is a worldwide federation of national standards bodies (ISO member bodies). The work of preparing International Standards is normally carried out through ISO technical committees. Each member body interested in a subject for which a technical committee has been established has the right to be represented on that committee. International organizations, governmental and non-governmental, in liaison with ISO, also take part in the work. ISO collaborates closely with the International Electrotechnical Commission (IEC) on all matters of electrotechnical standardization.

The procedures used to develop this document and those intended for its further maintenance are described in the ISO/IEC Directives, Part 1. In particular, the different approval criteria needed for the different types of ISO documents should be noted. This document was drafted in accordance with the editorial rules of the ISO/IEC Directives, Part 2 (see www.iso.org/directives).

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For an explanation of the voluntary nature of standards, the meaning of ISO specific terms and expressions related to conformity assessment, as well as information about ISO's adherence to the World Trade Organization (WTO) principles in the Technical Barriers to Trade (TBT), see www.iso.org/iso/foreword.html.

This document was prepared by Technical Committee ISO/ TC 229, *Nanotechnologies*.

Any feedback or questions on this document should be directed to the user's national standards body. A complete listing of these bodies can be found at www.iso.org/members.html.

Introduction

This document provides guidance for measuring and reporting the size and shape distributions of nanometer-scale particles using images acquired by the scanning electron microscope (SEM). This document applies to the SEM-based measurement of larger particles also. Nanoparticles are three-dimensional (3D) objects, but the SEM image is only a two-dimensional (2D) representation of the 3D shape from a certain viewing angle. The SEM image carries valuable information about the size and shape of particles. While the SEM image does contain a certain amount of 3D information, for sake of simplicity, this document does not deal with reconstructing 3D information. Rigorous three-dimensional characterization of nanoparticles would include size, shape, surface structure (e.g. texture), surface and internal material composition, and their locations in the investigated 3D volume. This document deals with two attributes of morphology, size and shape, for discrete and aggregated nano-objects (materials with at least one dimension in the nanometer-scale, i.e. within 1 nm to 100 nm). Suitable sample preparation is essential to obtaining high-quality electron microscope images and preferred techniques often vary with the sample material. It is equally important to make sure that the SEM itself is suitable to carry out the measurements with the required uncertainty. Typical guidance suggests that a large number, several hundreds or thousands of particles need to be measured for statistically sound size and shape distribution results. The actual number of nano-objects needed to be measured depends on the sample, the required uncertainty and on the performance of the SEM. Statistical evaluation of the data and the evaluation of uncertainty of the measurands are included as part of the measurement and reporting procedures.

This document contains measurement procedures, particle and data analysis and reporting clauses. In the Annexes, there are specific examples for measurements and guidance for the qualification of the SEM for reliable quantitative measurements. Automation of the image acquisition and data analysis can reduce cost and improve the quality of the results. Measurements of samples of discrete nanoparticles are generally easier to carry out with automated image acquisition and particle analysis systems. Measurements of complex discrete nanoparticles, and aggregates or agglomerates of nanoparticles may require operator-assisted image acquisition and analysis. Evaluation of particle shape is facilitated by many pertinent analysis software solutions that allow for automatic selection of various shape attributes as well.